

Abstract

Methods for producing electron emitter structures, the electron emitter structures produced, and field emission displays and field emission backlights incorporating the electron emitter structures

A procedure is proposed for forming an electron emitter structure for use in a field emission display, or as a field emission backlight for an LCD display. The electron emitter structure is formed by depositing mask elements 20 onto an laminar Al substrate 10, and etching the Al substrate chemically through gaps between the mask elements 20, such that a spikes 13 are formed on the substrate. These spikes 13 are then covered with an electron emitter material 21. The spikes 13 can be formed with a desired pitch/height ratio.

[Fig. 3(h)]

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